

10/561830

Docket No.: SHIGA7.040APC

Customer No. 20,995

IAP20 RECEIVED TO 22 DEC 2005

INFORMATION DISCLOSURE STATEMENT

Applicant	:	Hayashi et al.
App. No	:	<del>Unknown</del> 10/561830
Filed	:	Herewith
For	:	POSITIVE RESIST COMPOSITION AND METHOD OF FORMING RESIST PATTERN
Examiner	:	<del>Unknown</del> Ponder Thompson-Rummel
Art Unit	:	<del>Unknown</del> 1753

Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

Dear Sir:

Enclosed for filing in the above-identified application is a PTO/SB/08 Equivalent listing 18 references to be considered by the Examiner. Also enclosed are 16 foreign patent references and/or non-patent literature as listed on the Information Disclosure Statement. Please note the relevance of references 3 through 10 is that they are cited in the International Search Report from PCT ~~priority~~ application serial no. PCT/JP2004/009455.

This Information Disclosure Statement is being filed within three months of the filing date, and no fee is required.

Respectfully submitted,

KNOBBE, MARTENS, OLSON & BEAR, LLP

Dated: 22 Dec. 2005

By: Daniel E. Altman

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10/561830 PTO/SB/08 Equivalent  
10/561830

<b>INFORMATION DISCLOSURE STATEMENT BY APPLICANT</b>  (Multiple sheets used when necessary)	Application No.	Unknown
	Filing Date	Herewith
	First Named Inventor	Hayashi, Ryotaro
	Art Unit	Unknown
SHEET 1 OF 1		Attorney Docket No. SHIGA7.040APC Examiner Ponder Thompson-Rummel DEC 2005

U.S. PATENT DOCUMENTS					
Examiner Initials	Cite No.	Document Number Number - Kind Code (if known) Example: 1,234,567 B1	Publication Date MM-DD-YYYY	Name of Patentee or Applicant	Pages, Columns, Lines Where Relevant Passages or Relevant Figures Appear
/P.T.R./	1	US 2003/0203309 A1	10-30-2003	Nishimura et al.	
/P.T.R./	2	US 2002/0132181 A1	09-19-2002	Nishimura et al.	

FOREIGN PATENT DOCUMENTS						
Examiner Initials	Cite No.	Foreign Patent Document Country Code-Number-Kind Code Example: JP 1234567 A1	Publication Date MM-DD-YYYY	Name of Patentee or Applicant	Pages, Columns, Lines Where Relevant Passages or Relevant Figures Appear	T <sup>1</sup>
/P.T.R./	3	JP 2003-84436	03-19-2003			
/P.T.R./	4	JP 2003-173026	06-20-2003			
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/P.T.R./	11	JP 2881969	02-05-1999	Fujitsu Ltd.		Abstract
/P.T.R./	12	JP 05-346668	12-27-1993	Fujitsu Ltd.		X
/P.T.R./	13	JP 07-234511	09-05-1995	Fujitsu Ltd.		X
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/P.T.R./	15	JP 09-090637	04-04-1997	Fujitsu Ltd.		X
/P.T.R./	16	JP 10-161313	06-19-1998	Fujitsu Ltd.		X
/P.T.R./	17	JP 10-319595	12-04-1998	Fujitsu Ltd.		X
/P.T.R./	18	JP 11-012326	01-19-1999	Fujitsu Ltd.		X

NON PATENT LITERATURE DOCUMENTS			
Examiner Initials	Cite No.	Include name of the author (in CAPITAL LETTERS), title of the article (when appropriate), title of the item (book, magazine, journal, serial, symposium, catalog, etc.), date, page(s), volume-issue number(s), publisher, city and/or country where published.	T <sup>1</sup>

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Examiner Signature /Ponder Thompson Rummel/	Date Considered 08/29/2007
*Examiner: Initial if reference considered, whether or not citation is in conformance with MPEP 609. Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.	

T<sup>1</sup> - Place a check mark in this area when an English language Translation is attached.